IN THE CLAIMS

Please amend the claims as follows:

Claim 1 (Currently Amended): A go no-go gauge for verifying whether a <u>plasma</u> process <u>chamber</u> kit part used within a plasma chamber of a plasma processing tool has accumulated excessive wear or deposits, comprising:

a main body configured to be grasped by a user of the go no-go gauge;

a verifying feature configured to verify whether a dimension of a feature of the process kit part violates a prescribed size tolerance, wherein a violation of the prescribed tolerance indicates excessive wear of the process kit part or excessive material deposits on the process kit part; and

an identification feature configured to uniquely associate the go no-go gauge with at least one of said <u>plasma</u> process <u>chamber</u> kit part and a process to which the <u>process plasma</u> chamber kit part will be exposed.

Claim 2 (Original): The go no-go gauge of Claim 1, wherein the main body comprises at least one of Teflon, plastic, metal, and a composite material.

Claim 3 (Original): The go no-go gauge of Claim 1, further comprising a company identification mark visibly provided on a surface of the go no-go gauge.

Claim 4 (Original): The go no-go gauge of Claim 1, further comprising a tool configured to perform a simple function other than said verifying whether a dimension of a feature of the process kit part violates a prescribed size tolerance.

Claim 5 (Original): The go no-go gauge of Claim 4, wherein said tool comprises at least one of a screwdriver, a measuring scale and a letter opener.

Claim 6 (Currently Amended): The go no-go gauge of Claim 1, wherein said verifying feature comprises a plurality of verifying features each configured to verify whether a dimension of a feature of the process chamber kit part violates a prescribed size tolerance.

Claim 7 (Original): The go no-go of Claim 1, wherein the verifying feature comprises a protrusion for verifying that the dimension exceeds the prescribed size tolerance.

Claim 8 (Original): The go no-go of Claim 1, wherein the verifying feature comprises a protrusion for verifying that the dimension is smaller than the prescribed size tolerance.

Claim 9 (Original): The go no-go of Claim 1, wherein the verifying feature comprises a cavity for verifying that the dimension exceeds the prescribed size tolerance.

Claim 10 (Original): The go no-go of Claim 1, wherein the verifying feature comprises a cavity for verifying that the dimension is smaller than the prescribed size tolerance.

Claim 11 (Currently Amended): The go no-go gauge of Claim 1, wherein the identification feature comprises a unique configuration of said verification feature that is specific to said process chamber kit part.

Claim 12 (Currently Amended): The go no-go gauge of Claim 1, wherein the identification feature comprises a unique marking that specifies at least one of said process chamber kit part, a feature of the process chamber kit part and a process to which the process chamber kit part will be exposed.

Claim 13 (Currently Amended): The go no-go gauge of Claim 12, wherein said unique marking comprises at least one of a color and a symbol associated with said at least one of said process chamber kit part, said feature of the process chamber kit part and said process.

Claim 14 (Original): A method for verifying whether a process kit part used within a plasma chamber of a plasma processing tool has accumulated excessive wear or deposits, comprising:

determining a go no-go gauge associated with said process kit part, the go no-go gauge having a verification feature configured to verify whether a dimension of a process kit part feature violates a prescribed size tolerance, wherein a violation indicates the process kit part has accumulated excessive deposits of material or experienced excessive wear; and

applying the verification feature to the process kit part in a prescribed manner to verify whether the violation has occurred.

Claim 15 (Original): The method of Claim 14, wherein said determining comprises determining a go no-go gauge associated with said process kit part based on an identification feature provided on said go no-go gauge.

Claim 16 (Original): The method of Claim 15, wherein said determining comprises determining a go no-go gauge associated with the process kit part based on at least one of a symbol, a color, and a word provided on said go no-go gauge.

Claim 17 (Original): The method of Claim 14, wherein said determining comprises determining a go no-go gauge associated with said process kit part based on information not provided on said go no-go gauge.

Claim 18 (Original): The method of Claim 14, wherein said applying comprises applying the verification feature to the process kit part while the process kit part is mounted within a semiconductor processing chamber.

Claim 19 (Original): The method of Claim 14, wherein said applying comprises applying said verifying feature to the process kit part after said process kit part is removed from a semiconductor processing chamber.

Claim 20 (Original): The method of Claim 14, further comprising determining whether to clean or replace said process kit part based on said applying step.

Claim 21 (Original): The method of Claim 14, further comprising using said go nogo gauge to perform a simple function other than said verifying function.

Claim 22 (Original): The method of Claim 21, wherein said simple function is at least one of screwing a screw and measuring a dimension other than said dimension of a feature of the process kit part.

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Claim 23 (Original): The method of Claim 14, wherein said applying comprises verifying that a dimension of the process kit part is smaller than a prescribed size tolerance.

Claim 24 (Original): The method of Claim 14, wherein said verifying comprises verifying that a dimension of the process kit part exceeds the prescribed size tolerance.

Claim 25 (Currently Amended): A go no-gauge for verifying whether a <u>plasma</u> process <u>chamber</u> kit part used within a plasma chamber of a plasma processing tool has accumulated excessive wear or deposits, comprising:

a means for verifying whether a dimension of a feature of the process kit part violates a prescribed size tolerance, wherein a violation of the prescribed tolerance indicates excessive wear of the process kit part or excessive material deposits on the process kit part; and

means for uniquely associating the go no-go gauge with at least one of said <u>plasma</u> process <u>chamber</u> kit part, a feature of said <u>plasma</u> process <u>chamber</u> kit part, and a process to which the plasma chamber process kit part will be exposed.

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